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Citation for final published version:

Jang, Hyeon-Sik, Kim, Tae-Hoon, Kim, Byeong Geun, Hou, Bo , Lee, In-Hwan, Jung, Su-Ho, Lee, Jae-Hyun, Cha, SeungNam, Yang, Cheol-Woong, Kim, Byung-Sung and Whang, Dongmok 2021. Self-catalytic growth of elementary semiconductor nanowires with controlled morphology and crystallographic orientation. *Nano Letters* 21 (23) , pp. 9909-9915. 10.1021/acs.nanolett.1c02982

Publishers page: <http://dx.doi.org/10.1021/acs.nanolett.1c02982>

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Self-catalytic growth of Elementary Semiconductor Nanowires with Controlled Morphology and Crystallographic Orientation

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3 **Abstract:** While the orientation-dependent properties of semiconductor nanowires have been
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5
6 theoretically predicted, their study has long been overlooked in many fields owing to the limits to
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8 control the crystallographic growth direction of nanowires (NWs). We present here the orientation-
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10 controlled growth of single-crystalline germanium (Ge) NWs using a self-catalytic low-pressure
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12 chemical vapor deposition process. By adjusting the growth temperature, the orientation of growth
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14 direction in GeNWs was selectively controlled to the $\langle 110 \rangle$, $\langle 112 \rangle$, or $\langle 111 \rangle$ directions on the
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16 same substrate. The NWs with different growth directions exhibit distinct morphological features,
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18 allowing control of the NW morphology from uniform NWs to nanoribbon structures.
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21 Significantly, the VLS-based self-catalytic growth of the $\langle 111 \rangle$ oriented GeNW suggests that NW
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23 growth is possible for single elementary materials even without an appropriate external catalyst.
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25 Furthermore, these findings could provide opportunities to investigate the orientation-dependent
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28 properties of semiconductor NWs.
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31 **Keywords:** chemical vapor deposition, germanium, nanowire, orientation control, self-catalytic
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35 growth.
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3 Semiconductor NWs are promising building blocks for nanoscale electronic and optoelectronic
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5 applications due to their unique one-dimensional structure, quantum confinement effects, and
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7 compatibility with existing semiconductor technologies.¹⁻⁴ Over the past two decades, varieties of
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9 semiconductor NWs have been realized through well-developed growth techniques which allow
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11 control of the structures, morphologies, and compositions.⁵⁻¹⁰ However, the crystallographic
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13 control over the growth orientations of semiconductor NWs remains a significant challenge.
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15 Numerous theoretical and experimental studies have suggested that the properties of NW are
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17 strongly dependent on its crystallographic direction. For example, theoretically, the specific crystal
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19 orientations might induce a unique electronic structure with an indirect-to-direct energy gap
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21 transition and enhanced carrier mobility under strong quantum confinement effects.¹¹⁻¹⁴
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23 Experimental studies have also revealed that the crystal orientations of semiconductor NWs have
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25 a significant role in determining the different mechanical, piezoelectric, and photovoltaic
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27 properties of NW-based electronic and energy-harvesting devices.¹⁵⁻¹⁸ These studies related to
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29 orientation-dependent properties of NWs have provoked investigations for control of NW
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31 orientation via metal catalyst engineering, templated synthesis, or metal-assisted chemical
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33 etching.¹⁹⁻²⁴ In particular, the preferred growth direction of the NWs grown by vapor-liquid-solid
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35 (VLS) growth and oxide-assisted growth (OAG) have been intensively studied. In group-IV
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37 elementary semiconductors, such as Si and Ge, single-crystalline NWs grown by VLS approach
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39 using metal catalyst predominantly grow along the $\langle 111 \rangle$ direction.²⁵⁻²⁶ In contrast, $\langle 112 \rangle$ or
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41 $\langle 110 \rangle$ directions are energetically favored for NWs grown using the OAG process.²⁷⁻²⁸ In our
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43 previous study, a self-catalytic growth method was suggested to synthesize single-crystalline
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45 silicon (Si) and germanium (Ge) NWs.²⁹ Control over the diameter and in-situ doping of the
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47 semiconductor NWs also demonstrated that this method is well suited for electronic device
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3 applications. Here, we demonstrate that the orientation of the self-catalytic GeNWs can be
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5 controlled with the $\langle 110 \rangle$, $\langle 112 \rangle$, and $\langle 111 \rangle$ growth directions. Through a detailed analysis of
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7 the NW growth phenomena, the growth mechanism and the crystal orientation dependence of the
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9 GeNWs were investigated. In particular, in-depth studies for the growth behavior and the
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11 morphology of $\langle 111 \rangle$ oriented NWs strongly suggest the NWs have been grown through the self-
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13 catalytic VLS process. Furthermore, the NWs with different growth directions exhibit distinct
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15 morphological features, allowing control of the NW morphology from uniform NWs to 2D-like
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17 NRs structures.
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22 Self-catalytic GeNWs grown at low temperature ($T_g < 320 \text{ }^\circ\text{C}$) with the high partial pressure
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24 of Ge precursor (GeH_4) have random growth directions (Fig. S1 in supporting information).
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26 However, under low GeH_4 partial pressure, NWs predominantly grow in a specific
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28 crystallographic direction, and the direction can be controlled according to the growth temperature
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30 even on the same substrate (Fig. 1). The scanning electron microscope (SEM) image in Figure 1a
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32 shows uniform GeNWs grown at $340 \text{ }^\circ\text{C}$. When viewed along the $[100]$ direction of the substrate
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34 plane, the GeNWs are inclined at 45 ° and are consistent with the $\langle 110 \rangle$ growth direction. At
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36 $360 \text{ }^\circ\text{C}$, most NWs are grown along the $\langle 112 \rangle$ direction with a slightly tapered morphology (Fig.
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38 1b). The GeNWs grown at temperatures above $380 \text{ }^\circ\text{C}$ are aligned at a 90° angle normal to the
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40 substrate with the four fixed $\langle 111 \rangle$ directions, indicating the NWs are $\langle 111 \rangle$ oriented (Fig. 1c).
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43 Figures 1d-f show high-resolution transmission electron microscope (HRTEM) images and
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45 selected area electron diffraction (SAED) patterns near the tips of the $\langle 110 \rangle$, $\langle 112 \rangle$, and $\langle 111 \rangle$
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47 oriented single-crystalline GeNWs, respectively. The temperature dependence of the NW growth
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49 direction was further verified by the change in the NW growth direction according to the
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51 temperature change during growth (Fig. 2b and Fig. S2). Initially, $\langle 112 \rangle$ -oriented GeNWs having
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3 a rectangular cross-section were grown at 360 °C. When increasing the temperature up to 420 °C
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6 during the growth, the growth direction changes from $\langle 112 \rangle$ to $\langle 111 \rangle$, and the cross-sectional
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8 shape was also changed from rectangular to hexagonal shape.

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10 Based on the results, a possible mechanism for the orientation-controlled NW growth is
11 suggested (Fig. 2a). When supersaturation in the gas phase reaches a critical level, Ge nanocrystal
12 seeds can be nucleated on the reactive oxide surface.²⁹ At low growth temperature, the subsequent
13 formation of stable side facets promotes the anisotropic growth in the $\langle 110 \rangle$ or $\langle 112 \rangle$ direction
14 as precursor species are continuously supplied to the Ge nanowire tip with a high sticking
15 coefficient. In general, spontaneous growth of crystalline NWs usually progresses in a direction
16 that shows minimal surface energy at the NW growth tip. Among the low-index facets of Si and
17 Ge with diamond cubic structure, the $\{111\}$ and $\{100\}$ facets have the lowest and second-lowest
18 surface energy, respectively,³⁰ and thus $\langle 112 \rangle$ or $\langle 110 \rangle$ growth directions with $\{111\}$ and $\{100\}$
19 side facets are energetically favored for the group IV semiconductor NWs grown without an
20 external catalyst.^{27-28, 31} The related thermodynamic studies have been systematically conducted in
21 the Si and Ge NWs.³²⁻³³ As the temperature increases to 380 °C, the NW tips are presumed to exist
22 as a fully liquid state due to size-dependent melting point depression. Bulk Ge crystal has a high
23 melting temperature (937 °C). However, an in-situ TEM study recently demonstrated that Ge
24 nanoparticles with a diameter of approximately 20 nm readily melt even at temperatures below
25 400 °C.³⁴⁻³⁵ Because the liquid-solid interface at the growth tip prefers $\{111\}$ solid facets with the
26 lowest interface energy,³⁶ GeNWs can grow in the $\langle 111 \rangle$ growth directions perpendicular to the
27 $\{111\}$ surfaces, although the surface energy of NW sidewall is higher than that of NWs grown in
28 $\langle 110 \rangle$ and $\langle 112 \rangle$ directions (Fig. S3). For Si and Ge NWs, the $\langle 111 \rangle$ growth direction is a unique
29 feature observed only in VLS and VLS-like growth to the best of our knowledge.^{5, 32, 37}
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3 Furthermore, the $\langle 111 \rangle$ -oriented GeNWs with connected chain-like morphology were
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5 occasionally observed at the high growth temperature (Fig. S4). The lamellar twinning periodically
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7 occurs in the narrow neck of the spherical chains,³⁸⁻⁴¹ which is due to 2D ledge nucleation and
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9 epitaxial propagation occurring along the liquid-solid $\{111\}$ interface.⁴²⁻⁴³ Similar phenomena are
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11 also observed in crystal growth of undercooled Ge melt, favoring closed-packed $\{111\}$ facets at
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13 the liquid-solid interface.⁴⁴⁻⁴⁵ In general, compound solids, such as II-VI or III-V semiconductors,
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15 can grow anisotropically to 1D NWs through the VLS process even without an external catalyst
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17 because one of the elements can act as a liquid catalyst during the NW growth. However, VLS-
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19 based 1D growth of single-element materials has been limitedly studied only in materials, such as
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21 Si and Ge, for which suitable external metal catalysts are available.

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23 To investigate the orientation-dependent structural features, GeNWs with $\langle 110 \rangle$, $\langle 112 \rangle$, and
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25 $\langle 111 \rangle$ crystal directions were synthesized under GeH_4 partial pressure of 1.5 Torr with the flow
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27 rate of 40 sccm at 380°C (Fig. 3a). Although grown under the same conditions, the NWs exhibited
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29 characteristic morphological features depending on the crystal growth direction (Fig. 3b). While
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31 the $\langle 111 \rangle$ -oriented GeNWs are highly tapered with a relatively low growth rate, the $\langle 110 \rangle$ -
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33 oriented GeNWs had a much faster growth rate and uniform diameter. The $\langle 112 \rangle$ -oriented GeNW
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35 showed a moderate growth rate and tapering. Furthermore, it is worth mentioning that the axial
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37 and radial growth rates of GeNWs were strongly dependent on their crystallographic growth
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39 directions, which have rarely been studied before. These interesting phenomena can be explained
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41 by the geometric and thermodynamic properties of the semiconductor NWs enclosed by the crystal
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43 facets with different surface energies. The $\{112\}$ side plane enclosing $\langle 111 \rangle$ -oriented GeNW with
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45 hexagonal cross-section has relatively higher surface energy compared with the other low-index
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47 planes.⁴⁶ Therefore, Ge adatoms from the vapor precursor species are easily incorporated at the
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3 side planes, promoting the radial growth in the $\langle 111 \rangle$ oriented GeNWs (Fig. 3c). On the other
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6 hand, $\langle 110 \rangle$ oriented GeNWs have the lowest-energy state owing to the presence of three $\{111\}$
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8 and three $\{100\}$ stable planes.³¹ Direct precursor impingement for radial growth is suppressed, and
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10 Ge adatoms easily diffuse up to the NW tip. As a result, the growth rate in the axial direction is
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12 much faster even under the same growth conditions, resulting in a uniform shape of $\langle 110 \rangle$ oriented
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15 GeNWs (Fig. 3e). The $\langle 112 \rangle$ oriented GeNW has a rectangular cross-section which consists of
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17 two $\{111\}$ and two $\{110\}$ side planes.⁴⁷ The slightly tapered morphology is related to the
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19 thermodynamic lateral growth on a specific side surface (Fig. 3d).

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22 The highly tapered GeNWs growing along the $[111]$ direction have sawtooth faceting along
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24 the entire NW length (Fig. 4a and Fig. S5). The periodicity of upward and downward $\{111\}$ facets
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26 is observed, accompanying high-index planes such as (115) , (557) , and (119) on the side surface
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29 of each $\{112\}$ of the $[111]$ oriented GeNW (Figs. 4c-e). This periodic faceting has often been
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31 observed in semiconductor NWs grown *via* metal-catalyzed VLS growth, and it has been attributed
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33 to liquid-solid instability, enhanced vapor-solid (VS) deposition, impurity diffusion, or other
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36 chemical species supplied from the gas phase.^{46, 48-50} However, the downward faceting observed
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38 at the base of $\langle 111 \rangle$ oriented GeNWs indicates that the periodic faceting results from the
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40 competition between interfacial instability and surface energy minimization at the high
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43 temperature (Fig. S6). The surface energy of $\{112\}$ side planes increases with the elongation of
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45 the NWs, leading to the periodic formation of the $(111)/(002)$ plane to stabilize the radial growth
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47 perpendicular to the liquid-solid interface of the $\langle 111 \rangle$ oriented GeNWs. In addition, continuous
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49 VS deposition at a high temperature can induce surface reconstruction on a side plane, resulting in
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52 the formation of the high-index planes.⁵¹⁻⁵² In contrast to the highly tapered $\langle 111 \rangle$ oriented
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54 GeNW, $\langle 110 \rangle$ oriented GeNW has very uniform morphology along the axial direction because
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3 the $\langle 110 \rangle$ oriented NWs are bounded by a large number of $\{111\}$ and $\{110\}$ planes having the
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5 lowest surface energy (Figs. 4f-h).⁵³⁻⁵⁴ Therefore, unintentional Ge deposition on $\langle 110 \rangle$ oriented
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7 GeNWs could be minimized, thus preventing the formation of tapered morphology of non-uniform
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9 dopant distribution along the NW length.⁵⁵⁻⁵⁶ Theoretical and experimental studies have also
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11 reported that stable $\langle 110 \rangle$ NWs can have significantly increased carrier mobility,⁵⁷⁻⁵⁸ indicating
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13 that the selective preparation of $\langle 110 \rangle$ oriented NWs may improve reliability as well as
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15 performance in electronic device applications of semiconducting NWs. Otherwise, the $\langle 112 \rangle$ -
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17 oriented NW of group-IV materials usually has a rectangular cross-section, and its sides consist of
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19 two low-energy $\{111\}$ and high-energy $\{110\}$ surfaces.⁴⁷ By taking advantage of the energy
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21 difference between the two different facets, we have grown flexible 2D-like GeNRs (Figs. 4i-k).
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23 Ge species can be preferentially adsorbed on unstable $\{110\}$ planes, eventually leading to
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25 morphological evolution from $\langle 112 \rangle$ oriented GeNWs to GeNRs. The large width to thickness
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27 ratio also reveals that the lateral growth on the $\{110\}$ planes simultaneously occurs and competes
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29 with the axial growth of the $\langle 112 \rangle$ NWs (Fig. S7). To further investigate the anisotropic lateral
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31 growth of the $\langle 112 \rangle$ oriented GeNWs, we enhanced lateral growth of the $\langle 112 \rangle$ NWs to $\langle 110 \rangle$
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33 directions using a two-step process, which clearly shows that different surface energies promote
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35 the preferential growth on the $\{110\}$ planes (Fig. S8). 2D semiconductor NRs are promising
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37 building blocks for flexible or stretchable electronics.⁵⁹⁻⁶⁰ However, bottom-up grown NRs have
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39 seldom been observed in group-IV semiconductor materials.
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46 In conclusion, we demonstrated that the crystal orientation of self-catalytic GeNWs could be
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48 selectively controlled by adjusting the growth temperature. At low temperature, the $\langle 110 \rangle$ oriented
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50 GeNWs mainly grow with a uniform diameter along the NW length, while at high-temperature
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52 growth, the $\langle 111 \rangle$ oriented GeNWs exhibit a highly tapered morphology. At an intermediate
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3 temperature, the <112> oriented GeNWs predominantly grow. We also demonstrated that different
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6 crystal orientations play an essential role in determining the geometrical and morphological
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8 features of NWs. In particular, the controlled evolution from rectangular GeNWs to flexible 2D-
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10 like GeNRs is an excellent example of the morphology-controlled growth of novel nanostructures.
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12 The results of this study may provide an opportunity to utilize the orientation-dependent properties
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14 of semiconductor NW in practical device applications. Furthermore, the self-catalytic growth of
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16 the <111> oriented Ge NWs suggests VLS-based NW growth may be possible for a wide range of
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18 single elementary materials even without an external catalyst.
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24 **Supporting Information**

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26 Detailed experimental procedures and Figures S1– S8. The Supporting Information is available
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28 free of charge at <http://pubs.acs.org>.
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36 **Notes**

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38 The authors declare no competing financial interest.
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41 **Acknowledgment**

42
43 This research was supported by the National Research Foundation (NRF-2021R1A2C2013378) of
44
45 the Ministry of Science and ICT of Korea and the Korea Basic Science Institute (KBSI) National
46
47 Research Facilities & Equipment Center (NFEC) grant funded by the Korea Ministry of Education
48
49 (No. 2019R1A6C1010031). BK acknowledges support from Basic Science Research Program
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3 through the National Research Foundation of Korea (NRF) funded by the Ministry of Education
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5 (2013R1A6A3A03063814).
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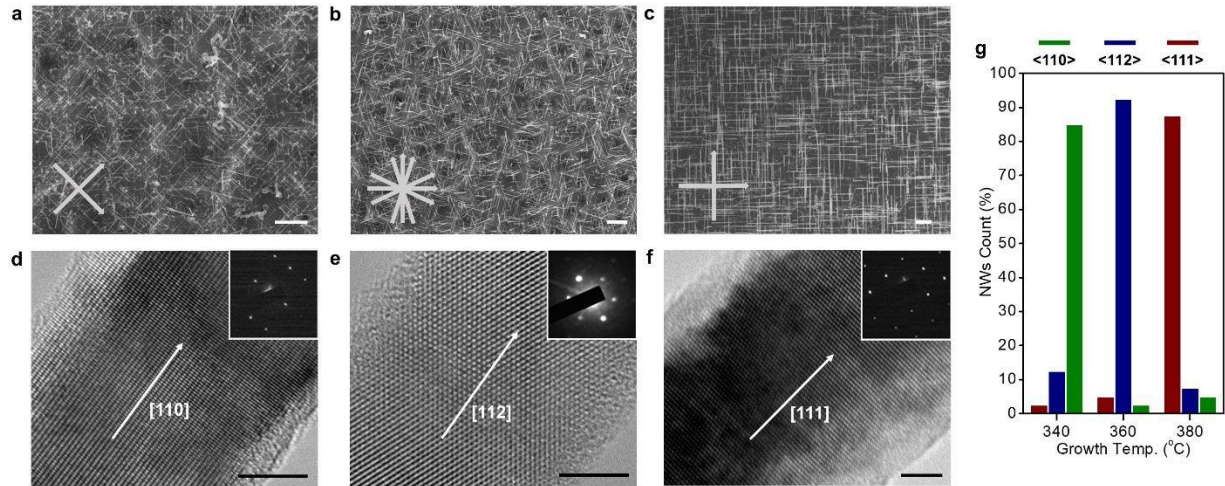


Figure 1. Temperature-dependent growth of <110>, <112>, and <111> oriented GeNWs. Plane-view SEM and HRTEM images with the corresponding SAED patterns of self-catalytic GeNWs epitaxially grown on Ge/Si (100) substrates at different temperatures and growth times with other conditions fixed. (a and d) <110> oriented GeNWs at 340 °C. (b and e) <112> oriented GeNWs at 360 °C. (c and f) <111> oriented GeNWs at 380 °C. Inserts show the schematics of the top view images of the <110>, <112>, and <111> directions on the substrate, respectively. Scale bars (a-c), 1 μ m. Scale bar (inset), 500 nm. Scale bars (d-f), 2 nm. (g) NW counts versus the corresponding growth temperature to control the NW orientation.

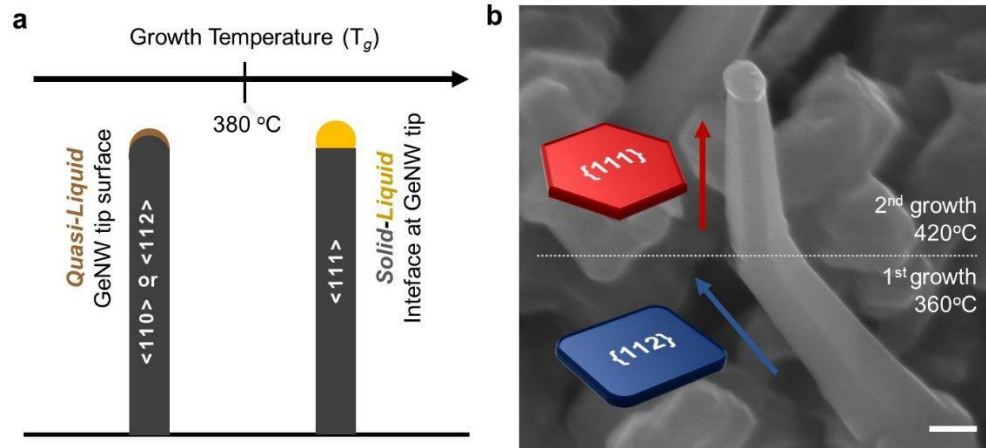


Figure 2. A suggested mechanism for orientation control and growth direction switching of GeNWs. (a) Schematic illustration of the self-catalytic growth of GeNWs with a preferential orientation by adjusting growth temperature. (b) An SEM image of the kinked GeNW grown by a two-step process, clearly showing the morphological transition from rectangular $\langle 112 \rangle$ to hexagonal $\langle 111 \rangle$ oriented GeNW. Insets show NW morphologies at the corresponding growth temperatures. Scale bar, 200 nm.

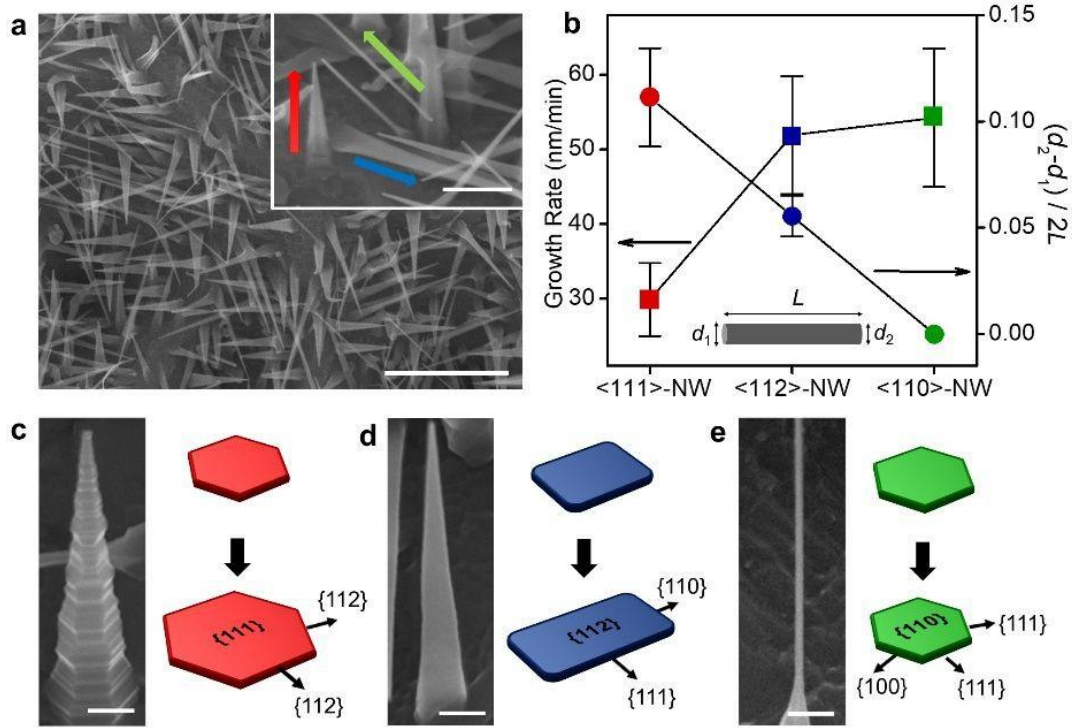


Figure 3. Orientation-dependent structural properties of GeNWs. (a) Top-view SEM images of self-catalytic GeNWs grown on Ge/Si(100) substrate at 380 °C with controlled GeH₄ partial pressure of 1.5 Torr. The inset image clearly shows the different NW morphologies and growth rates, dependent on the NW orientations. Scale bars, 200 nm. (b) Tapering degree and growth rate variations of GeNWs with different directions at the same growth condition. (c, d, and e) SEM images and schematic models of the <110>, <112>, and <111> oriented NWs exhibiting the different cross-sections and the orientation-modulated change of NW morphologies. Scale bars, 100 nm.

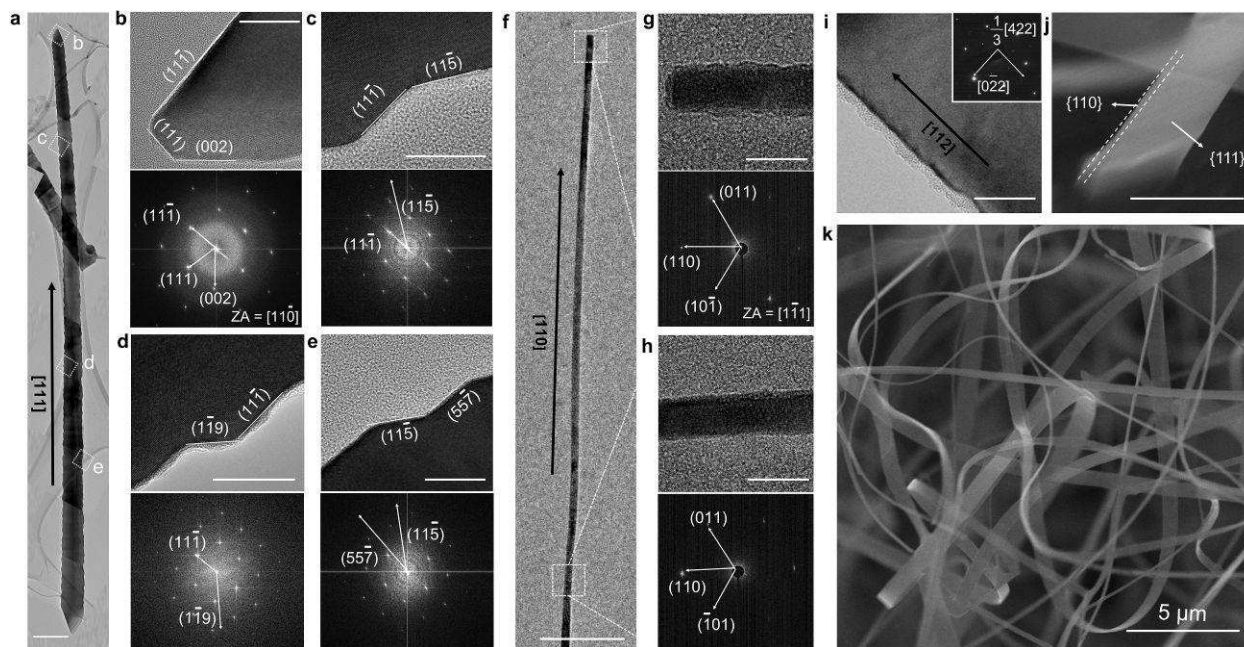


Figure 4. Crystal structure analysis according to the growth direction of GeNW. (a) Series of TEM and corresponding FFT images showing single crystal $[111]$ oriented NW. Scale bar, 200 nm. (b) Tip of GeNW faceted by low-index by low-index $(11\bar{1})$ and (002) planes. (c, d, and e) HR images of the sawtooth faceting with a regular periodicity. (f) HR images with the corresponding SAED patterns of $[110]$ oriented GeNW. (g) NW growth tip and (h) body with an atomically smooth surface. (i and j) SEM and TEM images of the single crystalline GeNRs, confirming that the GeNRs have a rectangular shape with two $\{111\}$ and two $\{110\}$ directions. The inset of (i) is an FFT image corresponding with the same GeNRs. (k) SEM image of GeNRs which evolved from $\langle 112 \rangle$ oriented GeNWs. Scale bars in (a), (f) and (j), 200 nm. Scale bars in (b-e), (g), (h), and (i), 20 nm.

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